

# Gary K Fedder

## List of Publications by Year in descending order

Source: <https://exaly.com/author-pdf/3535236/publications.pdf>

Version: 2024-02-01

193  
papers

4,982  
citations

101543

36  
h-index

114465

63  
g-index

248  
all docs

248  
docs citations

248  
times ranked

4208  
citing authors

#	ARTICLE	IF	CITATIONS
1	Aerosol-Jet-Printed Stretchable Electronic Decal Technology. , 2022, , .		0
2	High-€Conductivity Crack-€Free 3D Electrical Interconnects Directly Printed on Soft PDMS Substrates. Advanced Materials Technologies, 2022, 7, .	5.8	3
3	Stress-and-Temperature-Induced Drift Compensation on a High Dynamic Range Accelerometer Array Using Deep Neural Networks. , 2021, , .		3
4	Lateral Flexure Contact on CMOS MEMS Electrothermal Metal-Metal Contact Switch by Platinum ALD Sidewall Patterning. , 2021, , .		0
5	Interfacial delamination and delamination mechanism maps for 3D printed flexible electrical interconnects. Extreme Mechanics Letters, 2021, 43, 101199.	4.1	16
6	Hydrogel-based electrodes for selective cervical vagus nerve stimulation. Journal of Neural Engineering, 2021, 18, 055008.	3.5	8
7	Residual voltage as an ad-hoc indicator of electrode damage in biphasic electrical stimulation. Journal of Neural Engineering, 2021, 18, 0460c1.	3.5	1
8	Sidewall Metallization on CMOS MEMS by Platinum ALD Patterning. Journal of Microelectromechanical Systems, 2020, 29, 978-983.	2.5	8
9	A Reconfigurable High-Bandwidth CMOS-MEMS Capacitive Accelerometer Array with High-g Measurement Capability and Low Bias Instability. , 2020, , .		3
10	Mechanical characterization of polydimethylsiloxane (PDMS) exposed to thermal histories up to 300 Å°C in a vacuum environment. Journal of Micromechanics and Microengineering, 2020, 30, 067001.	2.6	10
11	In Memoriam Harvey C. Nathanson 1936-2019. Journal of Microelectromechanical Systems, 2020, 29, 2-2.	2.5	0
12	Inkjet Printing of Curing Agent on Thin PDMS for Local Tailoring of Mechanical Properties. Macromolecular Rapid Communications, 2020, 41, 1900569.	3.9	4
13	A High Dynamic Range CMOS-MEMS Accelerometer Array with Drift Compensation and Fine-Grain Offset Compensation. , 2019, , .		4
14	Frequency Staggered Accelerometer Array for Improved Ringdown Behavior. , 2019, , .		2
15	Hourglass-beam Nanogram-proof-mass Array: Toward a High Dynamic Range Accelerometer. , 2019, , .		3
16	ALD Titania Sidewalls on a CMOS-MEMS Resonator Oscillator and Effects on Resonant Frequency Drift. , 2019, , .		2
17	Resonant Microelectromechanical Receiver. Journal of Microelectromechanical Systems, 2019, 28, 327-343.	2.5	31
18	Compliant adhesive cuff electrode for selective stimulation in rat vagus nerve. , 2019, , .		2

#	ARTICLE	IF	CITATIONS
19	Ultra-compliant peripheral nerve cuff electrode with hydrogel adhesion. , 2018, , .		3
20	High dynamic range CMOS-MEMS capacitive accelerometer array. , 2018, , .		10
21	The role of hierarchical design and morphology in the mechanical response of diatom-inspired structures <i>via</i> simulation. Biomaterials Science, 2018, 6, 146-153.	5.4	16
22	Ultracompliant Hydrogelâ€Based Neural Interfaces Fabricated by Aqueousâ€Phase Microtransfer Printing. Advanced Functional Materials, 2018, 28, 1801059.	14.9	43
23	Insulation of thin-film parylene-C/platinum probes in saline solution through encapsulation in multilayer ALD ceramic films. Biomedical Microdevices, 2018, 20, 61.	2.8	1
24	A transfer process to fabricate ultra-compliant neural probes in dissolvable needles. Journal of Micromechanics and Microengineering, 2017, 27, 035008.	2.6	4
25	Drop casting of stiffness gradients for chip integration into stretchable substrates. Journal of Micromechanics and Microengineering, 2017, 27, 045018.	2.6	10
26	Stress Effects and Compensation of Bias Drift in a MEMS Vibratory-Rate Gyroscope. Journal of Microelectromechanical Systems, 2017, 26, 569-579.	2.5	44
27	CMOS-MEMS resonant demodulator for near-zero-power RF wake-up receiver. , 2017, , .		7
28	Reconfigurable AlN resonator filter design based on extended statistical element selection. , 2017, , .		0
29	On-chip environmental sensors for bias drift compensation. , 2017, , .		4
30	Ultra-low-power and high sensitivity resonant micromechanical receiver. , 2017, , .		9
31	Self-healing narrowband filters via 3D heterogeneous integration of AlN MEMS and CMOS chips. , 2017, , .		1
32	Self-healing narrowband filters via 3D heterogeneous integration of AlN MEMS and CMOS chips. , 2017, , .		2
33	Hermetic Wafer Level Thin Film Packaging for MEMS. , 2016, , .		4
34	Estimation of line dimensions in 3D direct laser writing lithography. Journal of Micromechanics and Microengineering, 2016, 26, 105011.	2.6	46
35	Processing of platinum electrodes for parylene-C based neural probes. , 2016, , .		4
36	A silicon neural probe fabricated using DRIE on bonded thin silicon. , 2016, 2016, 4885-4888.		2

#	ARTICLE	IF	CITATIONS
37	Elastic ribbon-like piezoelectric energy harvester for wearable devices with stretchable surfaces. , 2016, 2016, 4816-4819.		3
38	Ultra-miniature ultra-compliant neural probes with dissolvable delivery needles: design, fabrication and characterization. Biomedical Microdevices, 2016, 18, 97.	2.8	43
39	In vitro electrochemical characterization of polydopamine melanin as a tissue stimulating electrode material. Journal of Materials Chemistry B, 2016, 4, 3031-3036.	5.8	20
40	Material Gradients in Stretchable Substrates toward Integrated Electronic Functionality. Advanced Materials, 2016, 28, 3584-3591.	21.0	52
41	On-chip stress compensation on the ZRO of a mode-matched MEMS gyroscope. , 2016, , .		6
42	On-chip characterization of stress effects on gyroscope zero rate output and scale factor. , 2015, , .		9
43	Application of statistical element selection to 3D integrated AlN MEMS filters for performance correction and yield enhancement. , 2015, , .		8
44	Material Characterization and Transfer of Large-Area Ultra-Thin Polydimethylsiloxane Membranes. Journal of Microelectromechanical Systems, 2015, 24, 2170-2177.	2.5	10
45	Large stroke electrostatic actuated PDMS-on-silicon micro-pump. , 2015, , .		2
46	A tunable notch filter using high-k<math>\epsilon</math> lithium niobate resonators toward integration in filter banks. , 2015, , .		0
47	Nonlinearity tuning and its effects on the performance of a MEMS gyroscope. , 2015, , .		11
48	Engineered Material Gradients for Biologically Integrated Stretchable Electronics. Biophysical Journal, 2015, 108, 331a.	0.5	0
49	Modulation of Parylene-C to silicon adhesion using HMDS priming. Journal of Micromechanics and Microengineering, 2014, 24, 105001.	2.6	4
50	Release and transfer of large-area ultra-thin PDMS. , 2014, , .		3
51	Electrocaloric characterization of a poly(vinylidene fluoride-trifluoroethylene) copolymer. Letters, 2014, 105, .	3.3	27
52	Design and modeling of a fluid-based micro-scale electrocaloric refrigeration system. International Journal of Heat and Mass Transfer, 2014, 72, 559-564.	4.8	68
53	Tuning of nonlinearities and quality factor in a mode-matched gyroscope. , 2014, , .		3
54	Gas chemical sensitivity of a CMOS MEMS cantilever functionalized via evaporation driven assembly. Journal of Micromechanics and Microengineering, 2014, 24, 075001.	2.6	11

#	ARTICLE	IF	CITATIONS
55	Chronic tissue response to carboxymethyl cellulose based dissolvable insertion needle for ultra-small neural probes. <i>Biomaterials</i> , 2014, 35, 9255-9268.	11.4	170
56	Simulation of stress effects on mode-matched MEMS gyroscope bias and scale factor. , 2014, , .		15
57	Characterization of a CMOS sensing core for ultra-miniature wireless implantable temperature sensors with application to cryomedicine. <i>Medical Engineering and Physics</i> , 2014, 36, 1191-1196.	1.7	4
58	The use of coated gold nanoparticles in high performance chemical sensors. , 2014, , 231-253.		5
59	Effect of stress on matched-mode gyroscope frequencies. , 2014, , .		6
60	Ultra-low power frequency and duty-cycle modulated implantable pressure-temperature sensor. , 2013, , .		1
61	A Dual Probe STM Imaging System and a Low Noise Switched-Capacitor Transimpedance Amplifier. <i>IEEE Sensors Journal</i> , 2013, 13, 2984-2992.	4.7	7
62	Behavioral Modeling of a CMOSâ€MEMS Nonlinear Parametric Resonator. <i>Journal of Microelectromechanical Systems</i> , 2013, 22, 1447-1457.	2.5	12
63	Large-displacement parametric resonance using a shaped comb drive. , 2013, , .		17
64	Active CMOS-MEMS dual probe array for STM based parallel imaging and nanopatterning. , 2013, , .		1
65	SI-CMOS-MEMS dual mass resonator for extracting mass and spring variations. , 2013, , .		4
66	Interaction effects of temperature and stress on matched-mode gyroscope frequencies. , 2013, , .		16
67	Multiphysics modeling of a micro-scale Stirling refrigeration system. <i>International Journal of Thermal Sciences</i> , 2013, 74, 44-52.	4.9	9
68	Bi-State Bifurcation Control of a Shaped-Comb Parametric Resonator. , 2013, , .		0
69	Paper generators. , 2013, , .		69
70	Design and Evaluation of a MEMS-Based Stirling Microcooler. <i>Journal of Heat Transfer</i> , 2013, 135, .	2.1	9
71	A quadratic-shaped-finger comb parametric resonator. <i>Journal of Micromechanics and Microengineering</i> , 2013, 23, 095007.	2.6	23
72	Ultra-compliant neural probes are subject to fluid forces during dissolution of polymer delivery vehicles. , 2013, 2013, 1550-3.		2

#	ARTICLE	IF	CITATIONS
73	Bi-state control of a duffing microresonator on the falling edge of the instability. , 2013, , .		2
74	Bi-state control of parametric resonance. Applied Physics Letters, 2013, 103, 183512.	3.3	7
75	Design of a Fluid-Based Micro-Scale Electrocaloric Refrigeration System. , 2013, , .		2
76	Designing a robust high-speed CMOS-MEMS capacitive humidity sensor. Journal of Micromechanics and Microengineering, 2012, 22, 085021.	2.6	16
77	Statistical design and optimization for adaptive post-silicon tuning of MEMS filters. , 2012, , .		4
78	Numerical Modeling of a Micro-Scale Stirling Cooler. , 2012, , .		1
79	A high-speed, bimodal, CMOS-MEMS resonant scanner driven by temperature-gradient actuators. Proceedings of SPIE, 2012, , .	0.8	0
80	An ultra-low noise Switched Capacitor Transimpedance Amplifier for parallel Scanning Tunneling Microscopy. , 2012, , .		6
81	An ultra-compliant, scalable neural probe with molded biodissolvable delivery vehicle. , 2012, , .		43
82	A test structure to inform the effects of dielectric charging on CMOS MEMS inertial sensors. , 2012, , .		1
83	Behavioral modeling and testing of a CMOS-MEMS parametric resonator governed by the nonlinear Mathieu equation. , 2012, , .		3
84	Active CMOS-MEMS conductive probes and arrays for tunneling-based atomic-level surface imaging. , 2011, , .		5
85	A 4-bit RF MEMS phase shifter monolithically integrated with conventional CMOS. , 2011, , .		12
86	Self-engaging and disengaging CMOS-MEMS probes. , 2011, , .		0
87	2-DoF twisting electrothermal actuator for Scanning Laser Rangefinder application. , 2011, , .		2
88	Ultra-miniature wireless temperature sensor for thermal medicine applications. Proceedings of SPIE, 2011, 7901, .	0.8	1
89	CMOS-MEMS 3-bit Digital Capacitors With Tuning Ratios Greater Than 60:1. IEEE Transactions on Microwave Theory and Techniques, 2011, 59, 1238-1248.	4.6	20
90	Integrated vertical parallel-plate capacitive humidity sensor. Journal of Micromechanics and Microengineering, 2011, 21, 065028.	2.6	12

#	ARTICLE	IF	CITATIONS
91	A Frenkel-Poole model of dielectric charging in CMOS MEMS. , 2011, , .		3
92	Electrically driven CMOS-MEMS nonlinear parametric resonator design using a hierarchical MEMS circuit library. , 2011, , .		4
93	(Invited) CMOS MEMS Integration. ECS Transactions, 2011, 35, 331-340.	0.5	0
94	Design and Evaluation of MEMS-Based Stirling Cycle Micro-Refrigeration System. , 2011, , .		1
95	Refined Si-CMOS-MEMS process using AOE, drie and preform bonding. , 2011, , .		1
96	Enhancing CMOS Using Nanoelectronic Devices: A Perspective on Hybrid Integrated Systems. Proceedings of the IEEE, 2010, 98, 2061-2075.	21.3	5
97	Model for aspect ratio dependent etch modulated processing. Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films, 2010, 28, 334-346.	2.1	3
98	On the origin of selectivity and anisotropy loss during microstructure release etch. Journal of Micromechanics and Microengineering, 2010, 20, 035021.	2.6	8
99	CMOS-MEMS Capacitive Humidity Sensor. Journal of Microelectromechanical Systems, 2010, 19, 183-191.	2.5	68
100	High current low contact resistance platinum-coated CMOS-MEMS probes. , 2010, , .		2
101	Scaling of folded electrothermal actuators. , 2010, , .		0
102	Three-DOF CMOS-MEMS probes with embedded piezoresistive sensors. , 2010, , .		3
103	A Si-CMOS-MEMS process using back-side grinding. , 2010, , .		3
104	Active CMOS-MEMS AFM-like conductive probes for field-emission assisted nano-scale fabrication. , 2010, , .		6
105	Mechanisms of process-induced heating of MEMS structures during plasma release etch. , 2010, , .		1
106	Robust gold nanoparticles stabilized by trithiol for application in chemiresistive sensors. Nanotechnology, 2010, 21, 405501.	2.6	42
107	CMOS-MEMS Variable Capacitors Using Electrothermal Actuation. Journal of Microelectromechanical Systems, 2010, 19, 1105-1115.	2.5	19
108	Dielectric charging effects in electrostatically actuated CMOS MEMS resonators. , 2010, , .		10

#	ARTICLE	IF	CITATIONS
109	RF-CMOS-MEMS based frequency-reconfigurable amplifiers. , 2009, , .		3
110	A CMOS-MEMS rotary microactuator suitable for hard disk drive applications. , 2009, , .		3
111	Platinum sputtered CMOS-MEMS electrothermal probes with piezoresistive force sensing. , 2009, , .		0
112	Lever-Based CMOS-MEMS Probes for Reconfigurable RF IC's. , 2009, , .		3
113	Picogram material dosing of microstructures. Journal of Applied Physics, 2009, 106, 104913.	2.5	8
114	Design of a multi-axis implantable MEMS sensor for intraosseous bone stress monitoring. Journal of Micromechanics and Microengineering, 2009, 19, 085016.	2.6	19
115	CMOS-MEMS variable capacitors with low parasitic capacitance for frequency-reconfigurable RF circuits. , 2009, , .		10
116	CMOS-MEMS Capacitive Humidity Sensor. , 2009, , .		4
117	Aspect ratio dependent etch modulation for CMOS-MEMS applications. , 2009, , .		0
118	Polysilicon sensors for CMOS-MEMS electrothermal probes. , 2009, , .		6
119	Modeling and simulation of a condenser microphone. Sensors and Actuators A: Physical, 2008, 145-146, 224-230.	4.1	29
120	Technologies for Cofabricating MEMS and Electronics. Proceedings of the IEEE, 2008, 96, 306-322.	21.3	209
121	CMOS-MEMS Filters. , 2008, , .		5
122	CMOS-MEMS Lateral Electrothermal Actuators. Journal of Microelectromechanical Systems, 2008, 17, 103-114.	2.5	45
123	CMOS-MEMS probes for reconfigurable IC's. Proceedings of the IEEE International Conference on Micro Electro Mechanical Systems (MEMS), 2008, , .	0.0	7
124	Accelerometers. , 2008, , 135-180.		10
125	Tri-axial high-g CMOS-MEMS capacitive accelerometer array. Proceedings of the IEEE International Conference on Micro Electro Mechanical Systems (MEMS), 2008, , .	0.0	16
126	Modeling and Simulation of a Condenser Microphone. , 2007, , .		4



#	ARTICLE	IF	CITATIONS
127	Polymer Mass Loading of CMOS/MEMS Microslot Cantilever for Gravimetric Sensing. , 2007, , .		5
128	On-Chip High Quality Factor CMOS-MEMS Silicon-Fin Resonators. , 2007, , .		15
129	Electrostatic latching for inter-module adhesion, power transfer, and communication in modular robots. , 2007, , .		42
130	Silicon Undercut Characterization in a CMOS-MEMS Process. , 2007, , .		2
131	A schematic-based design model for microphone and circuit integration. , 2007, , .		2
132	An optimal design of high performance interface circuit with acoustic transducer model. , 2007, , .		5
133	Inkjet printed chemical sensor array based on polythiophene conductive polymers. Sensors and Actuators B: Chemical, 2007, 123, 651-660.	7.8	177
134	Volatile Organic Compound Detection Using Nanostructured Copolymers. Nano Letters, 2006, 6, 1598-1602.	9.1	195
135	Nanostructure Dependence of Conductive Polymer Chemical Sensors. , 2006, , .		3
136	Single-Crystal Silicon Based Electrothermal MEMS Mirrors for Biomedical Imaging Applications. , 2006, , 1429-1471.		2
137	Micro-electro-mechanical systems (MEMS)-based micro-scale direct methanol fuel cell development. Energy, 2006, 31, 636-649.	8.8	129
138	The Effect of a Distributed Mass Loading on the Frequency Response of a MEMS Mesh Resonator. , 2006, 2006, 1862-5.		0
139	A CMOS MEMS Gold Plated Electrode Array for Chemical Vapor Detection. , 2006, , .		5
140	System-Level Simulation of Microsystems. , 2006, , 187-227.		1
141	System-Level Simulation of Microsystems. , 2006, , 187-227.		1
142	Regioregular polythiophene nanowires and sensors. , 2005, , .		4
143	MEMS-based endoscopic optical coherence tomography. , 2005, , .		7
144	BiImplantable Bone Stress Sensor. , 2005, 2006, 518-21.		7

#	ARTICLE	IF	CITATIONS
145	Electrostatically actuated resonant microcantilever beam in CMOS technology for the detection of chemical weapons. IEEE Sensors Journal, 2005, 5, 641-647.	4.7	92
146	Temperature stabilization of CMOS capacitive accelerometers. Journal of Micromechanics and Microengineering, 2004, 14, 559-566.	2.6	41
147	A Two-Axis Electrothermal Micromirror for Endoscopic Optical Coherence Tomography. IEEE Journal of Selected Topics in Quantum Electronics, 2004, 10, 636-642.	2.9	121
148	Detection of free chloride in concrete by NMR. Cement and Concrete Research, 2004, 34, 379-390.	11.0	19
149	Position Control of Parallel-Plate Microactuators for Probe-Based Data Storage. Journal of Microelectromechanical Systems, 2004, 13, 759-769.	2.5	102
150	A low-noise low-offset capacitive sensing amplifier for a 50- $\mu\text{g}/\text{g}/\text{rad}/\text{Hz}$ monolithic CMOS MEMS accelerometer. IEEE Journal of Solid-State Circuits, 2004, 39, 722-730.	5.4	262
151	Thermo-Fluids Considerations in the Development of a Silicon-based Micro-scale Direct Methanol Fuel Cell. , 2004, , .		1
152	Endoscopic optical coherence tomographic imaging with a CMOS-MEMS micromirror. Sensors and Actuators A: Physical, 2003, 103, 237-241.	4.1	83
153	Endoscopic optical coherence tomography with a modified microelectromechanical systems mirror for detection of bladder cancers. Applied Optics, 2003, 42, 6422.	2.1	69
154	Fabrication, characterization, and analysis of a DRIE CMOS-MEMS gyroscope. IEEE Sensors Journal, 2003, 3, 622-631.	4.7	89
155	A CMOS-MEMS mirror with curled-hinge comb drives. Journal of Microelectromechanical Systems, 2003, 12, 450-457.	2.5	89
156	Integrated Microelectromechanical Gyroscopes. Journal of Aerospace Engineering, 2003, 16, 65-75.	1.4	79
157	Endoscopic optical coherence tomography with new MEMS mirror. Electronics Letters, 2003, 39, 1535.	1.0	43
158	Schematic-based lumped parameterized behavioral modeling for suspended MEMS. IEEE/ACM International Conference on Computer-Aided Design, Digest of Technical Papers, 2002, , .	0.0	15
159	<title>Modeling methodology for a CMOS-MEMS electrostatic comb</title>. , 2002, 4755, 114.		1
160	<title>Developments in chlorine detection in concrete using NMR</title>. , 2002, , .		1
161	Micromachined high-Q inductors in a 0.18- $\mu\text{m}$ copper interconnect low-k dielectric CMOS process. IEEE Journal of Solid-State Circuits, 2002, 37, 394-403.	5.4	110
162	A post-CMOS micromachined lateral accelerometer. Journal of Microelectromechanical Systems, 2002, 11, 188-195.	2.5	125

#	ARTICLE	IF	CITATIONS
163	Post-CMOS processing for high-aspect-ratio integrated silicon microstructures. Journal of Microelectromechanical Systems, 2002, 11, 93-101.	2.5	132
164	Vertical comb-finger capacitive actuation and sensing for CMOS-MEMS. Sensors and Actuators A: Physical, 2002, 95, 212-221.	4.1	84
165	Phase and Vibration Analysis for a CMOS-MEMS Gyroscope. International Journal of Nonlinear Sciences and Numerical Simulation, 2002, 3, .	1.0	3
166	Design of Direct Methanol Micro Fuel Cell Fluidic Systems. , 2002, , .		2
167	Endoscopic optical coherence tomography based on a microelectromechanical mirror. Optics Letters, 2001, 26, 1966.	3.3	279
168	A MEMS-based monolithic electrostatic microactuator for ultra-low magnetic disk head fly height control. IEEE Transactions on Magnetics, 2001, 37, 1915-1918.	2.1	4
169	<title>Mechanical effects of fatigue and charge on CMOS MEMS</title>. , 2000, 4180, 108.		8
170	Single-chip computers with microelectromechanical systems-based magnetic memory (invited). Journal of Applied Physics, 2000, 87, 6680-6685.	2.5	95
171	Emerging simulation approaches for micromachined devices. IEEE Transactions on Computer-Aided Design of Integrated Circuits and Systems, 2000, 19, 1572-1589.	2.7	79
172	A hierarchical circuit-level design methodology for microelectromechanical systems. IEEE Transactions on Circuits and Systems Part 2: Express Briefs, 1999, 46, 1309-1315.	2.2	85
173	Writing nanometer-scale pits in sputtered carbon films using the scanning tunneling microscope. Applied Physics Letters, 1999, 74, 3902-3903.	3.3	14
174	Hierarchical Mixed-Domain Circuit Simulation, Synthesis and Extraction Methodology for MEMS. Journal of Signal Processing Systems, 1999, 21, 233-249.	1.0	20
175	Hierarchical design and test of integrated microsystems. IEEE Design and Test of Computers, 1999, 16, 18-27.	1.0	30
176	<title>Characterization and reliability of CMOS microstructures</title>. , 1999, 3880, 132.		4
177	<title>Design and simulation of thermal actuators for STM applications in a standard CMOS process</title>. , 1999, 3875, 32.		2
178	Optimization-based synthesis of microresonators. Sensors and Actuators A: Physical, 1998, 70, 118-127.	4.1	33
179	Photolithographic Microfabrication. Handbook of Sensors and Actuators, 1998, , 13-61.	0.0	3
180	Multimode digital control of a suspended polysilicon microstructure. Journal of Microelectromechanical Systems, 1996, 5, 283-297.	2.5	46

#	ARTICLE	IF	CITATIONS
181	Laminated high-aspect-ratio microstructures in a conventional CMOS process. Sensors and Actuators A: Physical, 1996, 57, 103-110.	4.1	186
182	Process technology for the modular integration of CMOS and polysilicon microstructures. Microsystem Technologies, 1994, 1, 30-41.	2.0	72
183	Endoscopic optical coherence tomography with a micromachined mirror. , 0, , .		0
184	A direct plasma etch approach to high aspect ratio polymer micromachining with applications in bioMEMS and CMOS-MEMS. , 0, , .		6
185	RF CMOS-MEMS capacitor having large tuning range. , 0, , .		20
186	Accuracy and composability in NODAS. , 0, , .		1
187	A two-axis electrothermal SCS micromirror for biomedical imaging. , 0, , .		2
188	Issues in MEMS macromodeling. , 0, , .		14
189	Polymer wicking to mass load cantilevers for chemical gravimetric sensors. , 0, , .		3
190	CMOS-Based Sensors. , 0, , .		25
191	Silicon-Based Microdialysis Chip with Integrated Fraction Collection. , 0, , .		0
192	Volatile Organic Compound Discrimination Using Nanostructured Polythiophene Sensors. , 0, , .		2
193	"Chip-size" antennas for implantable sensors and smart dust. , 0, , .		5